

Declaration of Rachel J. Watters on Authentication of Publication

I, Rachel J. Watters, am a librarian, and the Head of Resource Sharing for the General Library System, Memorial Library, located at 728 State Street, Madison, Wisconsin, 53706. Part of my job responsibilities include oversight of Wisconsin TechSearch (“WTS”), an interlibrary loan department at the University of Wisconsin-Madison. I have worked as a librarian at the University of Wisconsin library system since 1998, starting as a graduate student employee in the Kurt F. Wendt Engineering Library and WTS, then as a librarian in Interlibrary Loan at Memorial Library. I began professional employment at WTS in 2002 and became WTS Director in 2011. In 2019, I became of Head of Resource Sharing for UW-Madison’s General Library System. I have a master’s degree in Library and Information Studies from the University of Wisconsin-Madison. Through the course of my studies and employment, I have become well informed about the operations of the University of Wisconsin library system, which follows standard library practices.

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Exhibit A to this Declaration is a true and accurate copy of the front and back covers, front matter, and back inside cover of the *Silicon Processing for the VLSI Era. Volume 3: The submicron MOSFET* (1995) publication, which includes a stamp on the inside back cover showing that this book is the property of the Kurt F. Wendt Library at the University of Wisconsin-Madison.

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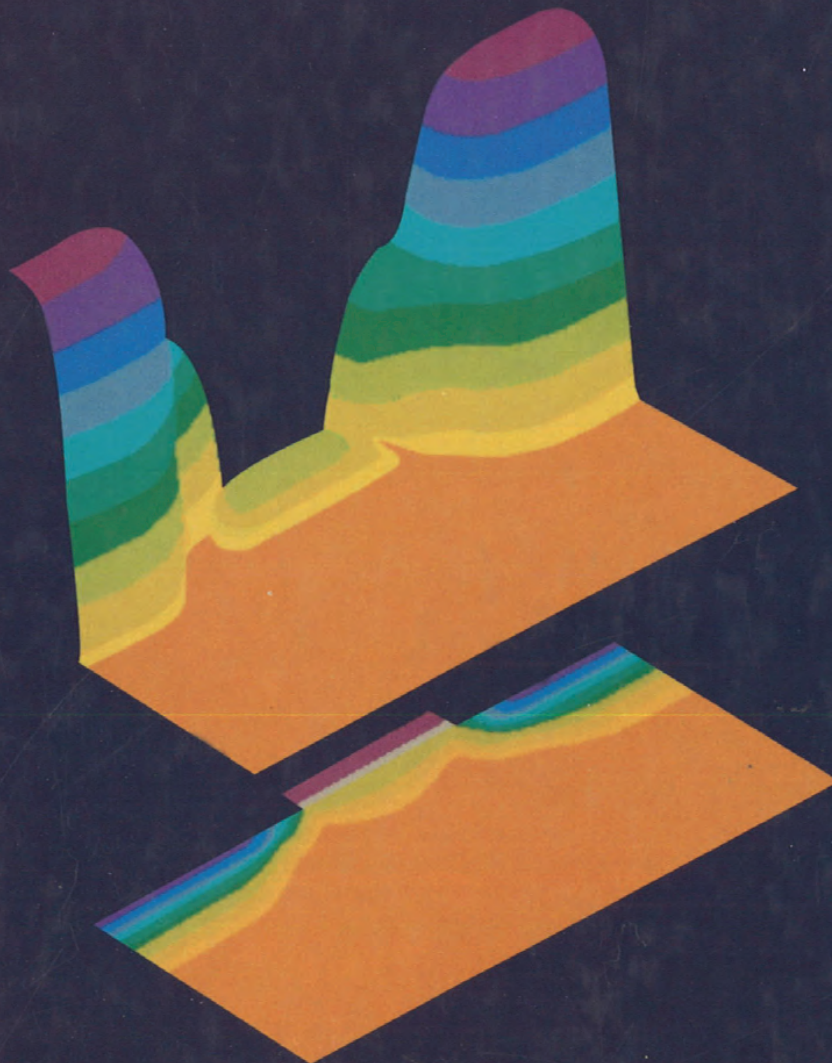
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EXHIBIT A

Silicon Processing

for the VLSI Era

Volume 3 - The Submicron MOSFET



S. Wolf

Silicon Processing

for the VLSI Era

B89066551995A

Volume 1 - Process Technology

By STANLEY WOLF and RICHARD N. TAUBER

TABLE of CONTENTS - Ch. 1 Silicon: Single-Crystal Growth and Watering; Ch. 2 Crystalline Defects, Thermal Processing, and Gettering; Ch. 3 Vacuum Technology for VLSI Applications; Ch. 4 Basics of Thin Films; Ch. 5 Silicon Epitaxial Film Growth; Ch. 6 Chemical Vapor Deposition of Amorphous and Polycrystalline Films; Ch. 7 Thermal Oxidation of Silicon Ch. 8 Diffusion in Silicon; Ch. 9 Ion Implantation for VLSI; Ch. 10 Aluminum Thin Films and Physical Vapor Deposition in VLSI; Ch. 11 Refractory Metals and Their Silicides in VLSI; Ch. 12 Lithography I: Optical Photoresists - Material Properties and Process Technology; Ch. 13 Lithography II: Optical Aligners and Photomasks; Ch. 14 Advanced Lithography: E-Beam and X-Ray; Ch. 15 Wet Processing: Cleaning, Etching, and Lift-Off; Ch. 16 Dry Etching for VLSI; Ch. 17 Material Characterization Techniques for VLSI Fabrication; Ch. 18 Structured Approach to Design of Experiments for Process Optimization.

1986 LATTICE PRESS 660 pp. ISBN 0-9616721-3-7

Volume 2 - Process Integration

By STANLEY WOLF

TABLE of CONTENTS - Ch. 1 Process Integration for VLSI and ULSI; Ch. 2 Isolation Technologies for Integrated Circuits; Ch. 3 Contact Technology and Local Interconnects for VLSI; Ch. 4: Multilevel Interconnect Technology for VLSI and ULSI; Ch. 5 NMOS Devices and Process Integration; Ch. 6 CMOS Process Integration; Ch. 7 Bipolar and BiCMOS Process Integration; Ch. 8 Semiconductor Memory Process Integration; Ch. 9 Process Simulation.

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Silicon Processing

for the VLSI Era

Volume 3

The

Submicron

MOSFET

S. Wolf

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1986
v.3

S.W



for the VLSI Era
Volume 3 - The Submicron MOSFET

**SILICON PROCESSING
FOR
THE VLSI ERA**

**VOLUME 3:
THE SUBMICRON MOSFET**

STANLEY WOLF Ph.D.
Professor, Department of Electrical Engineering
California State University, Long Beach
Long Beach, California

LATTICE PRESS

Sunset Beach, California

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22873617190002122

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Receiving date

02/12/2002

Expected receiving date

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Enumeration A

3

Enumeration B

-

Chronology I

-

Chronology J

-

Description

3

Pages

-

Pieces

1

Replacement cost

-

Receiving operator

import

Physical condition

-

Process type

Inventory Information

Inventory number

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Inventory date

-

Inventory price

-

Location Information

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Permanent location

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Source (Subfield 2)

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Storage location ID

-

Temporary Location Information

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Item is in temporary location

No

Temporary location

-

Temporary call number type

-

Temporary call number

-

Temporary source (Subfield 2)

-

Temporary item policy

-

Due back date

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Retention Reason

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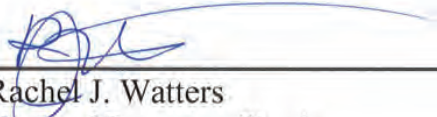
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EXHIBIT A

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**VOLUME 4:
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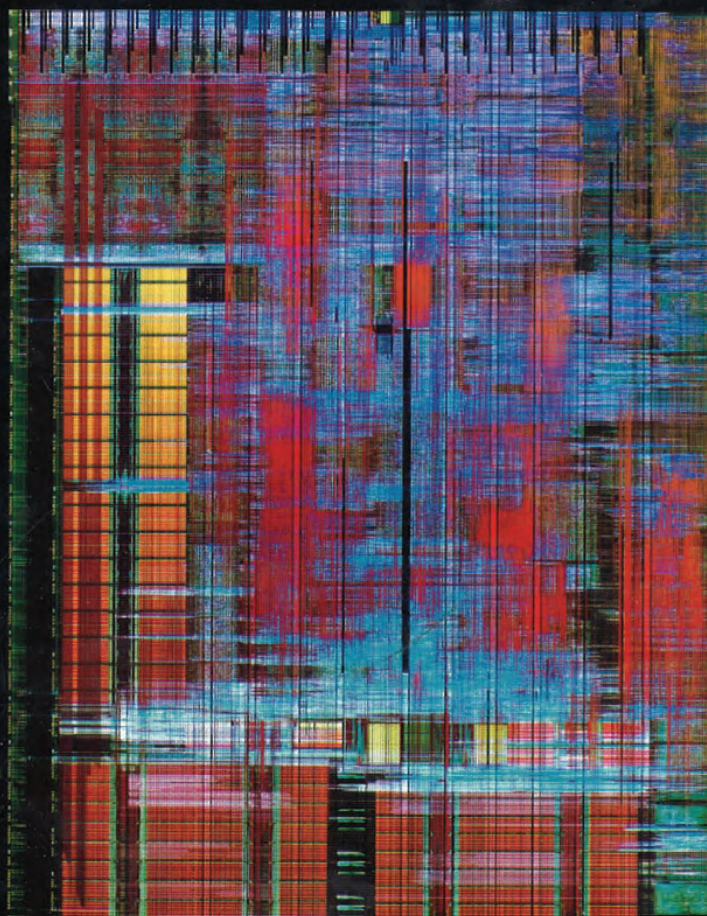


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SOLID STATE ELECTRONIC DEVICES



BEN G. STREETMAN ■ SANJAY BANERJEE

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- greatly expanded and updated discussion of device fabrication processes and CMOS integrated circuit technology, along with new data in the Appendices, provides a useful understanding of how semiconductor devices are made.
- extensive discussion of circuit and other application examples to provide students with feedback about the practical relevance of the theory.
- completely updated discussion of MOS devices, both in the underlying theory as well as the current preponderance of CMOS.
- updated, consolidated treatment of optoelectronic devices, including sources such as blue GaN-based LEDs and semiconductor vertical-cavity surface-emitting lasers, as well as detectors such as avalanche and resonant-cavity photodiodes.
- includes a listing of the key equations for semiconductor devices on the inside covers of the book, arranged thematically to help students digest the concepts.
- about 200 problems and current references which extend concepts in the text.



BEN G. STREETMAN is Dean of the College of Engineering at The University of Texas at Austin and holds the Dula D. Cockrell Centennial Chair in Engineering. He is a Professor of Electrical and Computer Engineering and was the founding Director of the Microelectronics Research Center. He has taught at the University of Illinois at Urbana-Champaign as well as the University of Texas at Austin. He has received numerous awards including the Education Medal of IEEE, The Frederick Emmons Terman Medal of the ASEE, and membership in the National Academy of Engineering. He has published more than 270 articles in the technical literature. Thirty-three students of Electrical Engineering, Materials Science, and Physics have received their Ph.D.s under his direction.



SANJAY BANERJEE is the Cullen Trust Endowed Professor of Electrical and Computer Engineering, and Director of the Microelectronics Research Center at The University of Texas at Austin. He has more than 225 archival refereed publications and 12 U.S. patents, and has supervised 18 Ph.D. students. His honors include the NSF Presidential Young Investigator Award (1988), the Texas Atomic Energy Centennial Fellowship (1990-1997), Distinguished National Lecturer for the IEEE Electron Devices Society (1997-), and Fellow of the IEEE (1996).

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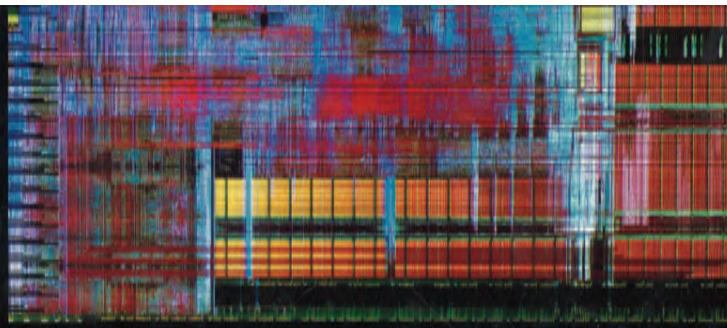
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This is the fifth edition of the most widely used introductory book on semiconductor materials, physics, devices and technology. Previous editions have been translated into Russian, Japanese and Polish. The book was written with two basic goals in mind: 1) develop the physics concepts to understand current and future devices; 2) provide a source of current semiconductor devices and technology so that their applications in microelectronic circuits and systems can be appreciated.

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- greatly expanded and updated discussion of device fabrication processes and CMOS integrated circuit technology, along with new data in the Appendices, provides a useful understanding of how semiconductor devices are made.
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FIFTH EDITION

Solid State Electronic Devices

BEN G. STREETMAN AND SANJAY BANERJEE

*Microelectronics Research Center
Department of Electrical and Computer Engineering
The University of Texas at Austin*



PRENTICE HALL
Upper Saddle River, New Jersey 07458

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Cover: **Fourth Generation PowerPC Microprocessor chip courtesy of Motorola, Inc.**

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Status	Item not in place	

General

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History

General Information

Barcode	89081141418
Copy ID	2
Material type	Book
Item policy	general (book)
Provenance	
Is magnetic	No
PO Line	 
Issue date	
Receiving date	01/22/2004  
Expected receiving date	
Enumeration A	
Enumeration B	
Chronology I	
Chronology J	
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Pieces	1
Replacement cost	
Receiving operator	import
Physical condition	
Process type	

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Inventory number	
Inventory date	
Inventory price	
Clear Inventory Information	

Location Information

Permanent location *

Item call number type

Item call number

Source (Subfield 2)

Storage location ID

Temporary Location Information

Item is in temporary location

No

☐

Yes

☐

Temporary location

Temporary call number type

Temporary call number

Temporary source (Subfield 2)

Temporary item policy

Due back date

Retention Information

Committed to Retain

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No

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Yes

Retention Reason

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